IN THE SPECIFICATION:

Page 10, paragraph 41, is amended as follows:

[0041] Figures 3a and 3b depict a schematic flow of substrates through a substrate processing system according to an embodiment of the invention. One or more substrates comprising a single lot (although a plurality of substrates can comprise more than one lot) are provided to track input port 20 and flow towards coater 12 of the track 10. After the coater 12, the lot flows toward the lithographic apparatus 9 where the substrate(s) are exposed. After completion of exposure, the lot flows towards the developer 14 ~~12~~ and then out of the track 10 through track output port 22. After each lot is introduced into the substrate processing system, another lot can be introduced thereafter in effect resulting in a series of lots (and substrates) flowing through the substrate processing system for substrate processing.

Page 16, paragraph 56, is amended as follows:

[0056] Further, it should be noted that in some cases rates and/or times of processing per lot type / recipe may not be uniform among all lots having the same lot type / recipe. For example, activities specific to a particular substrate of a lot may apply such as a metrology activity. In that case, the rate or time of processing cannot apply to all lots of the same type / recipe due to such per substrate variances in certain lots. Accordingly, in an extension of the above-described embodiments and implementations, such per substrate activities may be accounted for in the determination of lot order. Similarly, certain pre-conditions and/or post-conditions can affect the ordering of lots. Supply of materials to or performance of actions in a part of the substrate processing system, for instance, may impact an otherwise appropriate lot order. For example, substrates of a lot may not be ready for introduction into the part of the substrate processing system, processing materials (e.g. a resist) may not have been supplied to a part of the substrate processing system, a calibration or other test may not have been performed, etc., all of which can cause slowing of processing of lots. Accordingly, in an extension of the above-described embodiments and implementations, pre-conditions and/or post-conditions may be accounted for in the determination of the lot order.

Page 18, paragraph 59, is amended as follows:

[0059] With all the necessary information, the scheduler can determine an appropriate lot order as described in the above embodiments, implementations and/or their combinations. Of course, ~~any other~~ any other appropriate ordering algorithm may be applied to order the lots.